

Optical simulations of stray light on instrumented baffles surrounding Virgo end mirrors during O5

Adrian Macquet

Institut de Física d'Altes Energies (IFAE), Barcelona Institute of Science and Technology, E-08193 Barcelona, Spain



Institut de Física d'Altes Energies





Barcelona Institute of Science and Technology

Context and motivation

- Stray light is an important source of noise in Virgo
- Baffles to reduce scattered light in mirrors / core optics / arm tubes
 - Absorb 99.5% of diffused light
 - No active monitoring of stray light
- Instrumented baffles equipped with photodetectors to monitor scattered light
 - Help with laser alignment
 - Dynamic mapping of mirror surface
 - Monitor development of higher order modes in the beam
- → Phase I Instrumented baffle around IMC end mirror (done)
- → Phase II Instrumented baffles around end mirrors (EM) in main arms (being executed)





Instrumented baffle around IMC end mirror

See poster: *Stray Light Measurements With an Instrumented Baffle in the Advanced Virgo Input Mode Cleaner Cavity* by Machiel Kolstein

- A first instrumented baffle was installed in April 2021 around the IMC end mirror as a demonstrator for the technology
 - 76 photosensors + 16 temperature sensors
 - Currently operational
 - Good agreement between measurements and simulations

- → Monitor misalignment and mirror defects in IMC cavity
- → Help to calibrate future optical simulations
- → Design new instrumented baffles for Virgo main mirrors



O.Ballester et al., CQG, 2022

Planned design of EM instrumented baffle

- Baffle: r = 26 cm to 40 cm
- 5 rings of sensors (active area 0.49 cm²)
 - \circ 72 sensors at r = 27 / 28 / 29 cm
 - \circ 24 at r = 30 cm, 12 at r = 31 cm
- Final layout subject to modifications
 - Impact of sensors' reflectivity
 - Readout speed

Goals of simulations:

- Demonstrate benefits of instrumented baffles
- Find optimal design / dynamic range / resolution for sensors

Simulations of light distribution in Virgo main arms

Stationary Interferometer Simulation (SIS)

- FFT-based code
 - Simulate field propagation in a resonant cavity
 - Spatial distribution of field with given resolution
- Use realistic optical components
 - Mirror surface maps, cryobaffle...
 - Thermal deformation, coating absorption
- Introduce defects in the cavity
 - Misalignment, beam displacement
 - Defects on mirror surface



Principle of the simulations

- Simulate different configurations
 - Aligned cavity perfect mirrors
 - Aligned cavity realistic mirror maps
 - Misaligned cavity
 - Point absorbers on mirrors
- Get spatial distribution of power on mirrors
- Compute power in each sensor



Expected power on EM in nominal configuration (sensors in white)

Nominal configuration

Perfectly aligned cavity, realistic mirror maps, thermal deformation and coating absorption

- Measured O3 map for IM
- Simulated O5 map for EM
- ~ 390 kW circulating in the cavity
- Average power in sensors:
 - \circ $10^{\text{-4}}\,\text{W}$ from 27 to 30 cm
 - \circ 10⁻⁸ W at 31 cm (field clipped by cryobaffle)
- Non-isotropic distribution and large variance
 - Scattering from imperfect mirrors

Estimated power seen by each sensor (effective area 0.49 cm²)



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- → Spatial structure appears with realistic mirror maps in the inner layers
- → Scattering from mirrors -> ~ 10 times more power in sensors area

Misaligned cavity

Simulate misaligned cavity by introducing a tilt in the end mirror

- Decrease power in cavity
- Development of higher order modes in the beam
 - Decrease overall sensitivity
- Critical range: 0.1 1 µrad -> power drops from 95% to 10%



EM is rotated along the y axis, introducing a yaw angle (credit: H. Yamamoto)



Power circulating in cavity vs tilt angle

Misaligned cavity (2)



Power seen by each sensor with a tilt angle of 0.3 µrad (left) and 0.8 µrad (right)

Beam is off-centered w.r.t the center of the mirror: excess power in the direction of misalignment

Monitoring misalignment

Differential power along opposite sensors: $\Delta P(\phi, r) = P(\phi + \pi, r) - P(\phi, r)$

- Nominal configuration: 0 mean, variance $\sigma \sim 10^{-4}$ W
- Compute $\Delta P(phi, r) / \sigma$
 - SNR that quantifies misalignment

Conclusion:

- Sensors are able to monitor misalignment in the critical range 0.3 0.8 µrad
- Sensors closer to the mirror are most useful





SNR of the differential power for a tilt angle of 0.3 μrad

Large misalignment

When misalignment becomes too large (>~ 1 µrad), cavity lock is lost

- Cavity power drops
- Beam dominated by higher order modes
- Power in sensors in the inner rings can go up to ~1 W
 - Sensors will saturate
- Sensors in outer ring (31 cm) prove useful in this particular case



Surface power on EM for a tilt angle of 0.8 μrad





Point absorbers

Point absorber (PA): point-like defect in the mirror that generates scattered light

- Typical absorption: ~ 0.1 ppm
 - For 390 kW -> 50 mW (large value)

Sensors see an excess of power (>10 mW)

• Larger effect in outer rings

Power in sensors for a 50 mW PA located 1 cm to the right of the EM center



Beam shape with and without PA

Point absorbers (2)

PAs generate effects with high spatial resolution

- Sensors cannot map the precise distribution of surface power
- Difficult to interpret the output of sensors
 - Excess of power can indicate the presence of one or more PA's
 - Inferring position of PA is not possible



Surface power on EM with a 50 mW PA at 1 cm to the right of the center

Conclusion

- → Photosensors should see a power of ~ 10^{-4} W in nominal configuration from 27 to 30 cm
 - Large variance due to imperfect mirror surface maps
- → Misalignment can be monitored from ~ 0.3 μ rad
 - Beam off-centered by ~ 0.1 mm
 - 5% decrease in cavity power
 - Need sensors as close as possible to the mirror (r = 27 cm)
 - Sensors on outermost ring could help for very large misalignment
- → Point-like defects generate an excess of power in sensors
 - Not enough precision to infer the position of point absorbers

Complementary work:

- Estimate potential effect of instrumented baffle on Virgo's sensitivity curve (reflexion and backscattering from sensors)
- Consider layouts with less sensors (focus on alignment?)